In the Claims

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims

1. (Original) A transport system within a fabrication system, the fabrication system comprising a plurality of tools for processing articles, the transport system comprising a stocker and a track subsystems, wherein:

the stocker subsystem comprises:

a stocker body for storing the articles;

a plurality of load ports, located on the stocker body, enabling the articles to be transferred between the stocker body and the track subsystem, the number of which depends on properties of the tools; and

the track subsystem comprises a delivery part and a load part, comprising a plurality of branches corresponding to the load ports.

2. (Original) The transport system as claimed in claim 1, wherein the articles are semiconductor wafers.

3. (Original) The transport system as claimed in claim 1, wherein the stocker body further comprises an outward load port enabling the articles to be transferred between the stocker body and an outside system.

4. (Original) The transport system as claimed in claim 3, wherein the outward load port, linked with one of the branches, enables the articles to be transferred between the stocker body and the track subsystem.

5. (Original) A fabrication system, comprising:

a plurality of tools for processing articles; and

a transport system comprising a stocker subsystem and a track subsystem, wherein:

the stocker subsystem comprises:

a stocker body for storing the articles;

a plurality of load ports, located on the stocker body, enabling the articles to be transferred between the stocker body and the track subsystem, the number of load ports depending on properties of the tools; and

the track subsystem comprises delivery and load parts, the load parts comprising a plurality of branches corresponding to the load ports.

6. (Original) The fabrication system as claimed in claim 5, wherein the articles are semiconductor wafers.

7. (Original) The fabrication system as claimed in claim 5, wherein the stocker body further comprises an outward load port enabling the articles to be transferred between the stocker body and an outside system.

8. (Original) The fabrication system as claimed in claim 7, wherein the outward load port, linked with one of the branches, enables the articles to be transferred between the stocker body and the track subsystem.

9. – 11. (Canceled)

12. (Currently Amended) A transport method for controlling article transport in a fabrication system, comprising:

providing~~, wherein the fabrication system comprises~~ a plurality of tools;

providing ~~and~~ a transport system comprising stocker and track subsystems, wherein the stocker subsystem comprises a stocker body with a plurality of load ports, located on the stocker body, enabling the articles to be transferred between the stocker body and the track subsystem, the number of which depends on properties of the

tools, and the track subsystem comprises delivery and load parts with a plurality of branches corresponding to the load ports;~~, the method comprising:~~

~~determining~~ selecting one of the tools ~~the targeted tool of the articles~~;

~~determining~~ selecting one of the ~~a~~ load ports and ~~corresponding~~ one of the branches to deliver the articles in accordance with the status of the selected ~~targeted~~ tool, the load parts, and the load ports; and

issuing a transport demand to direct the transport system to transport the articles using ~~in accordance with~~ the selected load port and branch ~~route~~.

13. (Original) The transport method as claimed in claim 12, wherein the articles are semiconductor wafers.

14. (Currently Amended) A storage medium for storing a computer program providing a transport method for controlling article transport in a fabrication system, wherein the fabrication system comprises a plurality of tools and a transport system comprising stocker and track subsystems, wherein the stocker subsystem comprises a stocker body with a plurality of load ports, located on the stocker body, enabling the articles to be transferred between the stocker body and the track subsystem, the number of which depends on properties of the tools, and the track subsystem comprises delivery and load parts with a plurality of branches corresponding to the load ports, the method comprising:

receiving destination information ~~recording the targeted tool of the articles~~ indicating one of the tools;

~~determining~~ selecting one of the ~~a~~ load ports and ~~corresponding~~ one of the branches to deliver the articles in accordance with the status of the indicated~~targeted~~ tool, the load parts, and the load ports; and

issuing a transport demand to direct the transport system to transport the articles using ~~in accordance with~~ the selected load port and branch ~~route~~.

15. (Original) The storage medium as claimed in claim 14, wherein the articles are semiconductor wafers.